

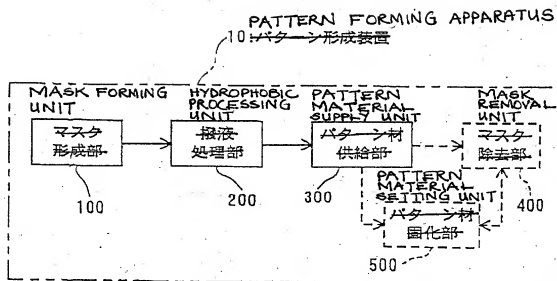
FIG.  
図 1

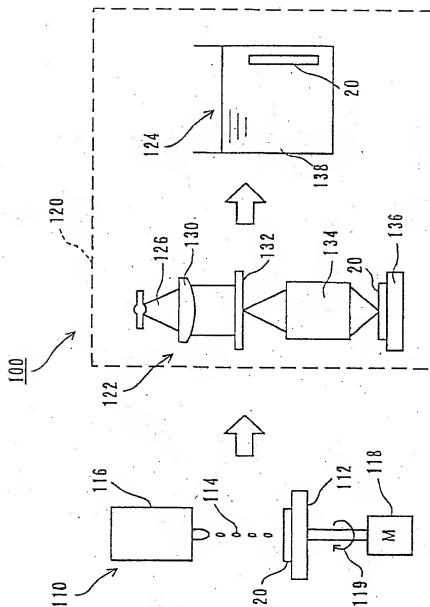
FIG.  
2

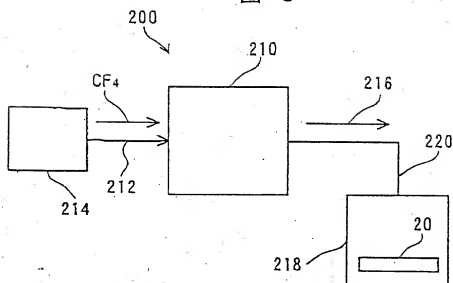
FIG.  
~~2~~ 3

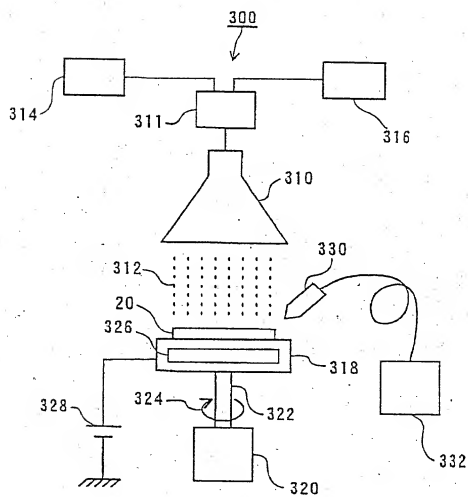
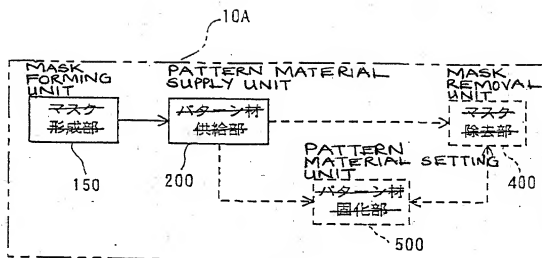
FIG.  
~~2~~ 4

FIG.  
図 5

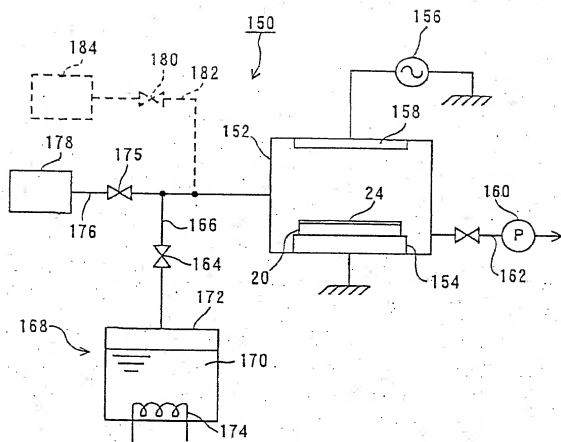
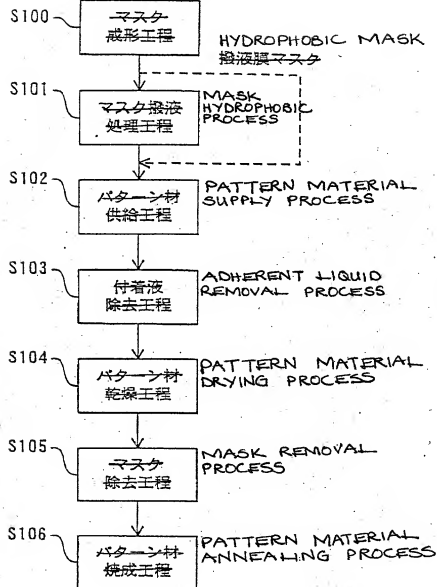


FIG.  
図 7MASK FORMING  
PROCESS

## MASK FORMING

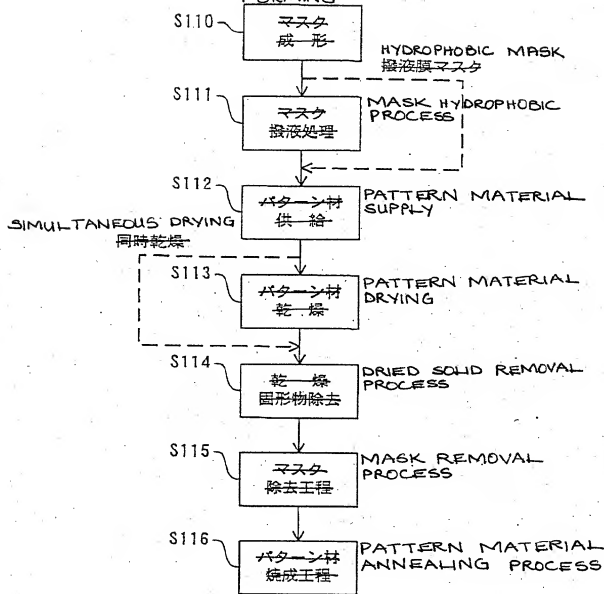




FIG.

9

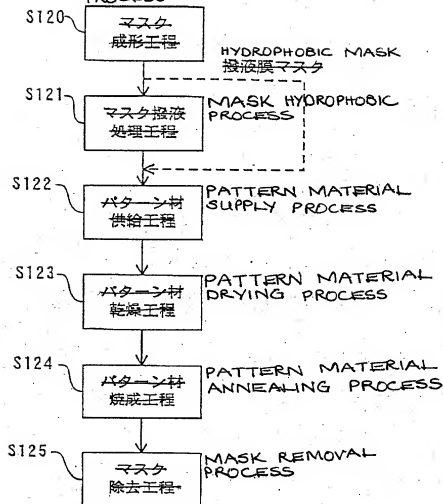
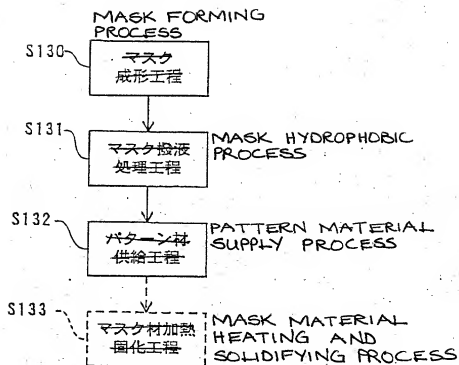
MASK FORMING  
PROCESS

FIG.  
図 10

MASK FORMING  
PROCESS

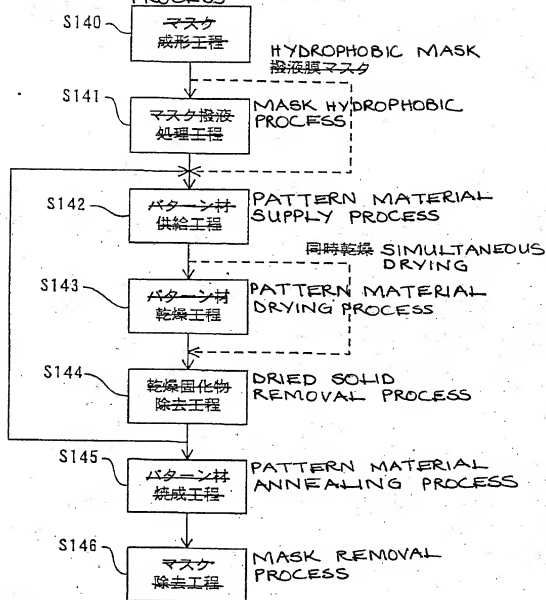


FIG.  
図 12  
MASK FORMING  
PROCESS

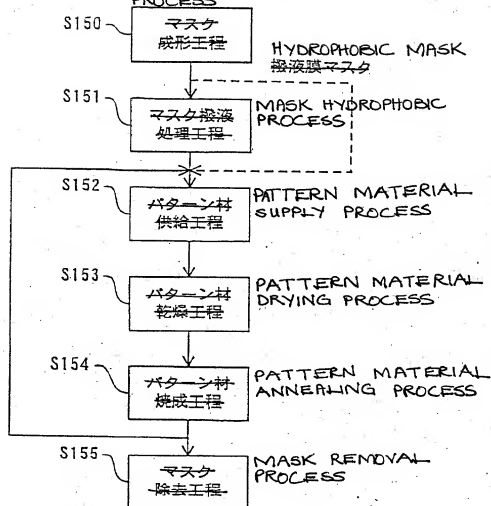


FIG.  
図 13  
WORKPIECE HYDROPHOBIC  
PROCESS

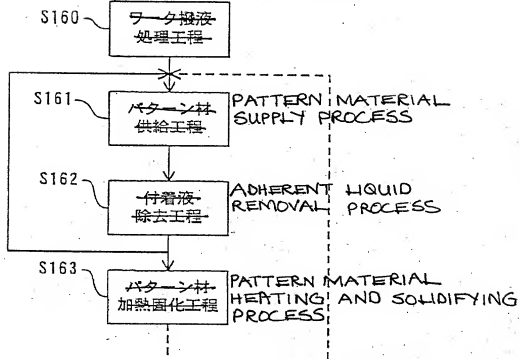


FIG. 14  
WORKPIECE HYDROPHOBIC  
PROCESS

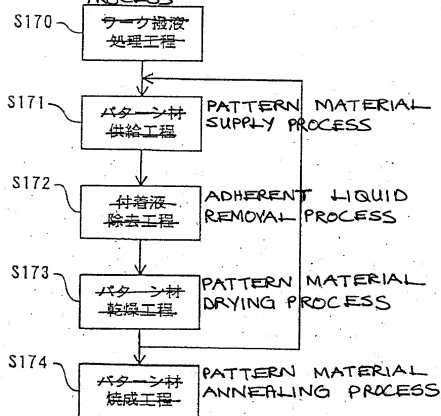


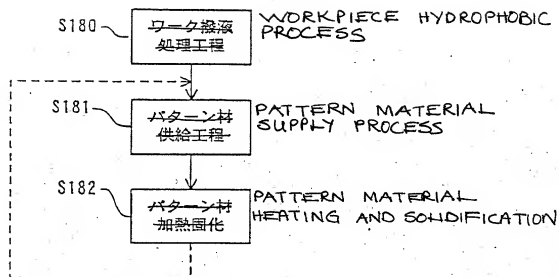
FIG.  
図 15

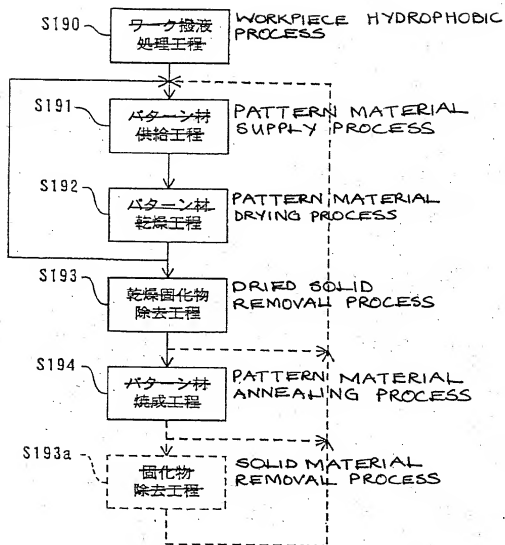
FIG.  
図 16



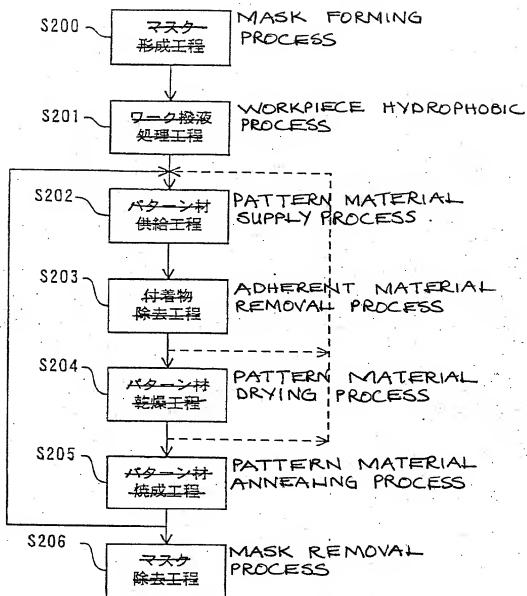
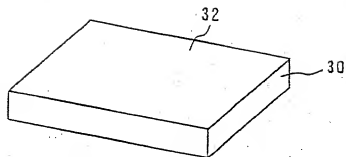
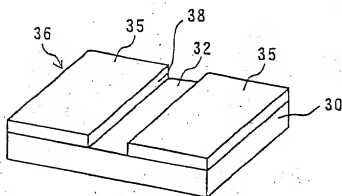
FIG.  
図 17

FIG.  
18

(1)



(2)



(3)

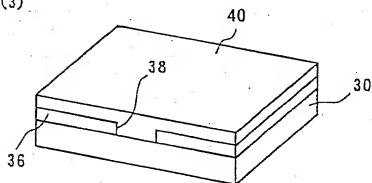
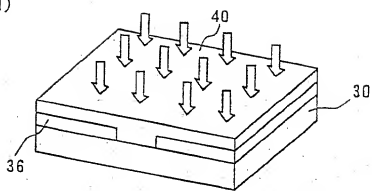
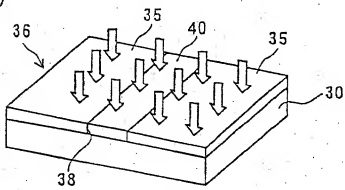


FIG.  
19

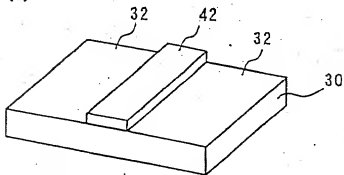
(1)



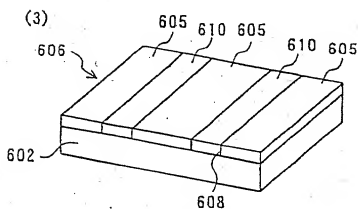
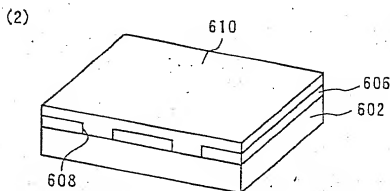
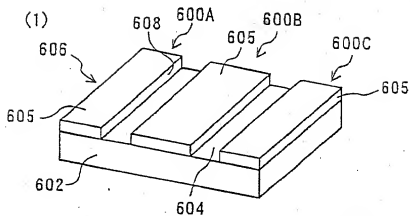
(2)



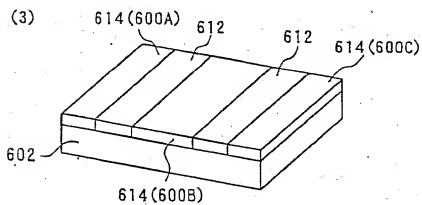
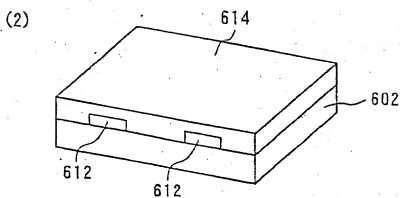
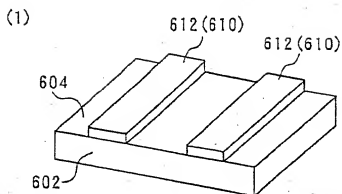
(3)

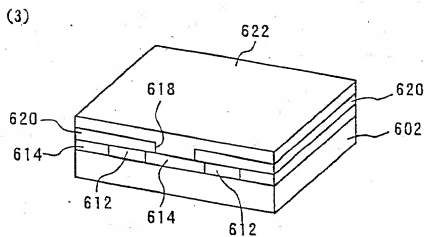
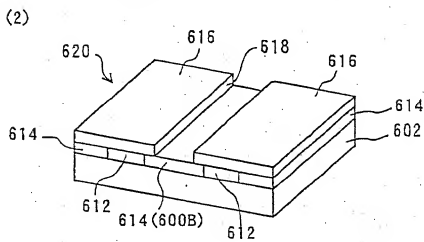
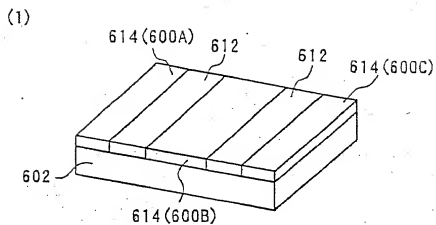


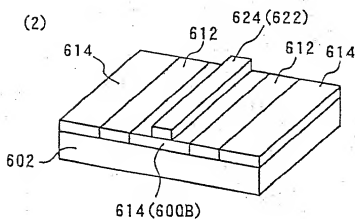
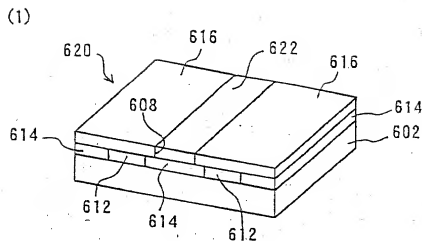
20/33  
FIG.  
20



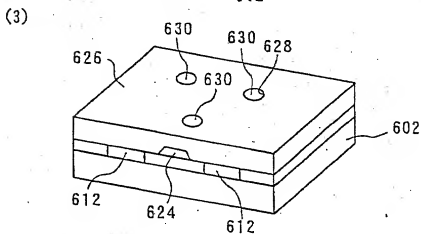
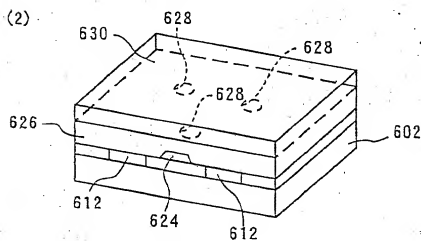
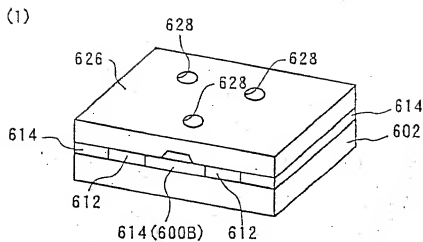
21/33  
FIG.  
~~21~~ 21





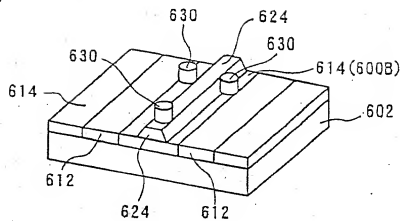


24/33  
FIG.  
24

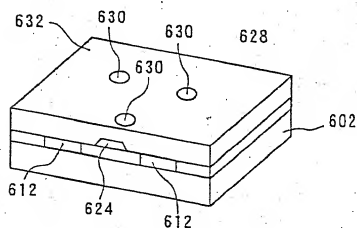




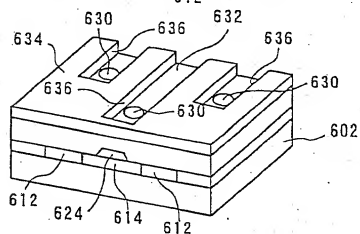
(1)



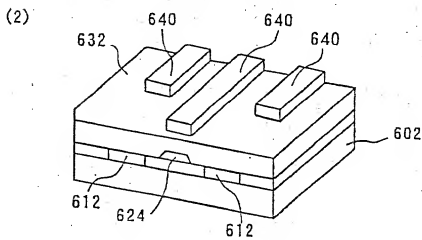
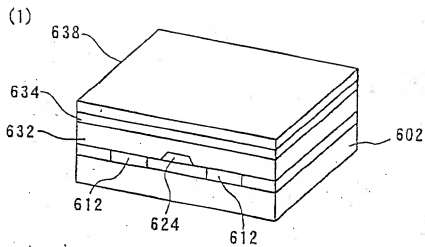
(2)



(3)



25/33  
FIG.  
26



27/33  
FIG.  
27

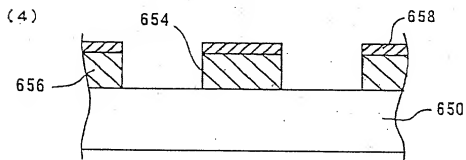
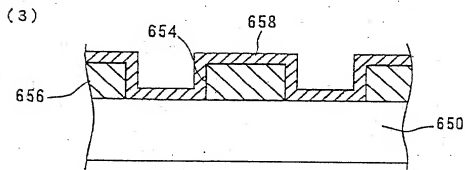
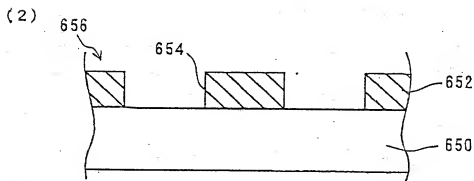
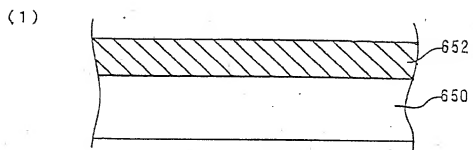
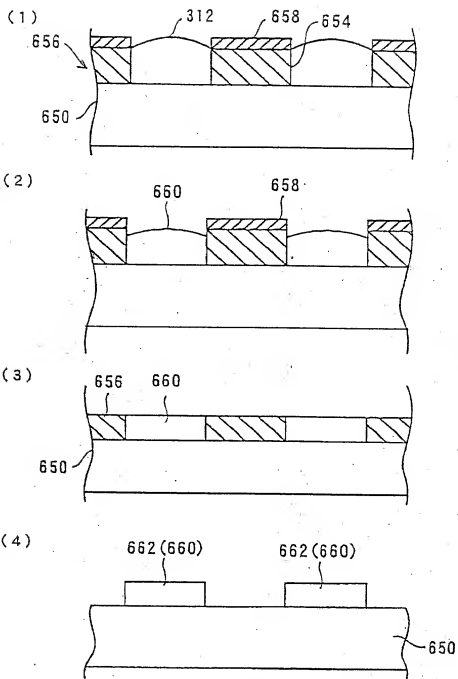
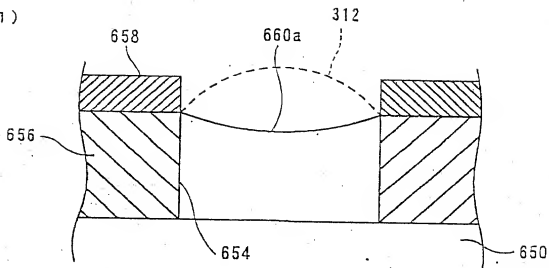
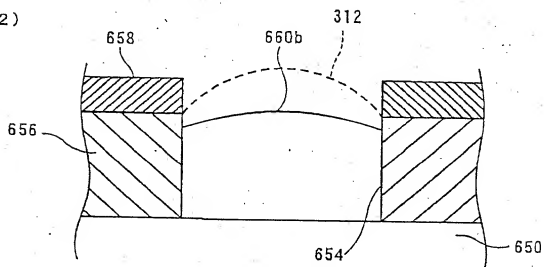


FIG.  
28

(1)



(2)



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FIG.  
30

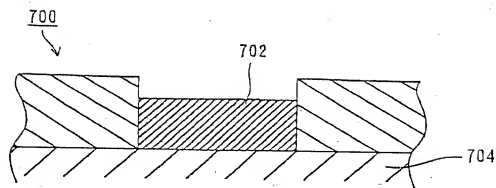
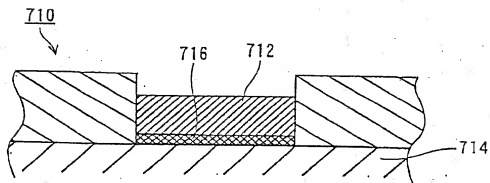


FIG.  
31



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FIG.  
~~32~~ 32

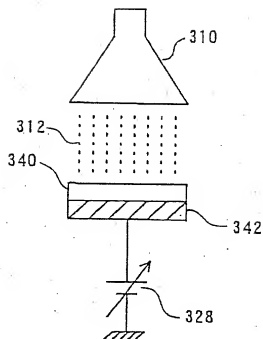
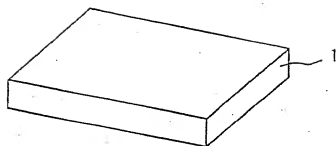
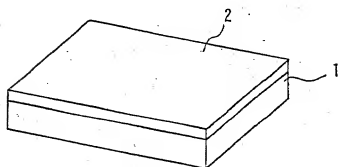


FIG.  
~~32~~ 33

(1)



(2)



(3)

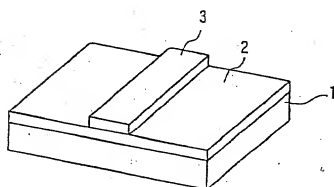




FIG.  
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